

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention	METHOD FOR IMAGE REVERSAL OF IMPLANT RESIST USING A SINGLE PHOTOLITHOGRAPHY EXPOSURE AND STRUCTURES FORMED THEREBY
Application Number :	10/709,285
Confirmation Number:	
First Named Applicant:	Steven Holmes
Attorney Docket Number:	FIS920030151US2 2826 Quach
Art Unit:	
Examiner:	
Search string:	(4564584 or 5266505 or 5306390 or 6015991 or 6221562 or 6309975 or 6358856 or 6372412 or 6448164 or 6489191 or 6503689 or 6562547 or 6559680 or 20020172896).pn

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
TG	1	4564584	1986-01-14	Fredericks et al.		430	312
TG	2	5266505	1993-11-30	Ahlgren et al.		437	31
TG	3	5306390	1994-04-26	Peek		156	659.1
TG	4	6015991	2000-01-18	Wheeler et al.		257	336
TG	5	6221562	2001-04-24	Boyd et al.	B1	430	314
TG	6	6309975	2001-10-30	Wu et al.	B1	438	705
TG	7	6358856	2002-03-19	Lyons et al.	B1	438	703
TG	8	6372412	2002-04-16	Hakey et al.	B1	430	325
TG	9	6448164	2002-09-10	Lyons et al.	B1	438	585
TG	10	6489191	2002-12-03	Shao et al.	B2	438	199
TG	11	6503689	2003-01-07	Zampinin et al.	B2	430	270.1
TG	12	6562547	2003-05-13	Kraft et al.	B2	430	314
TG	13	6559680	2003-07-29	Lin	B2	430	314

US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
TG	1	20020172896	2002-11-21	Adams et al.	A1	430	322

10/17/09, 285

Signature

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1/31/05

Examiner Name

Date